

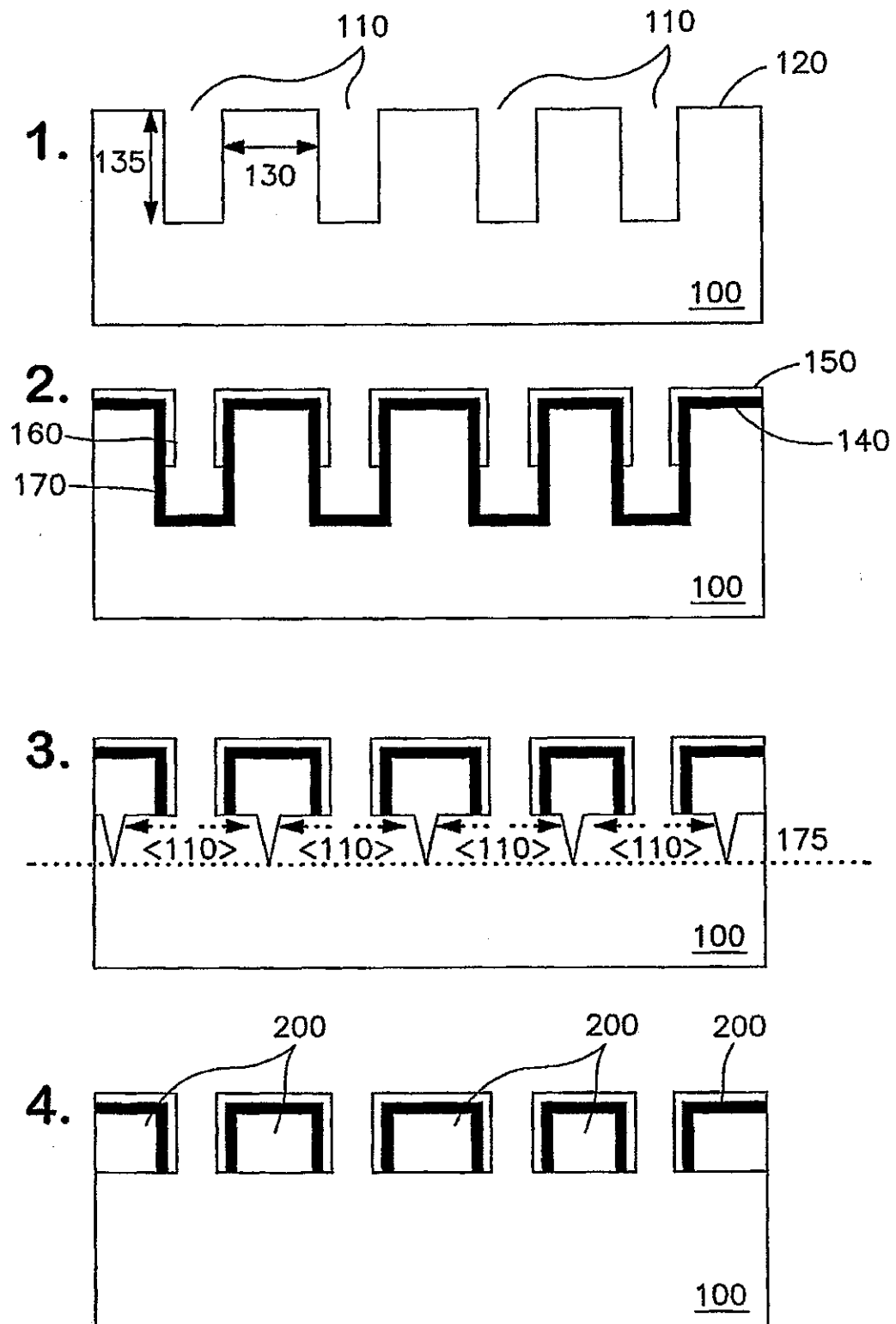


FIG. 1a

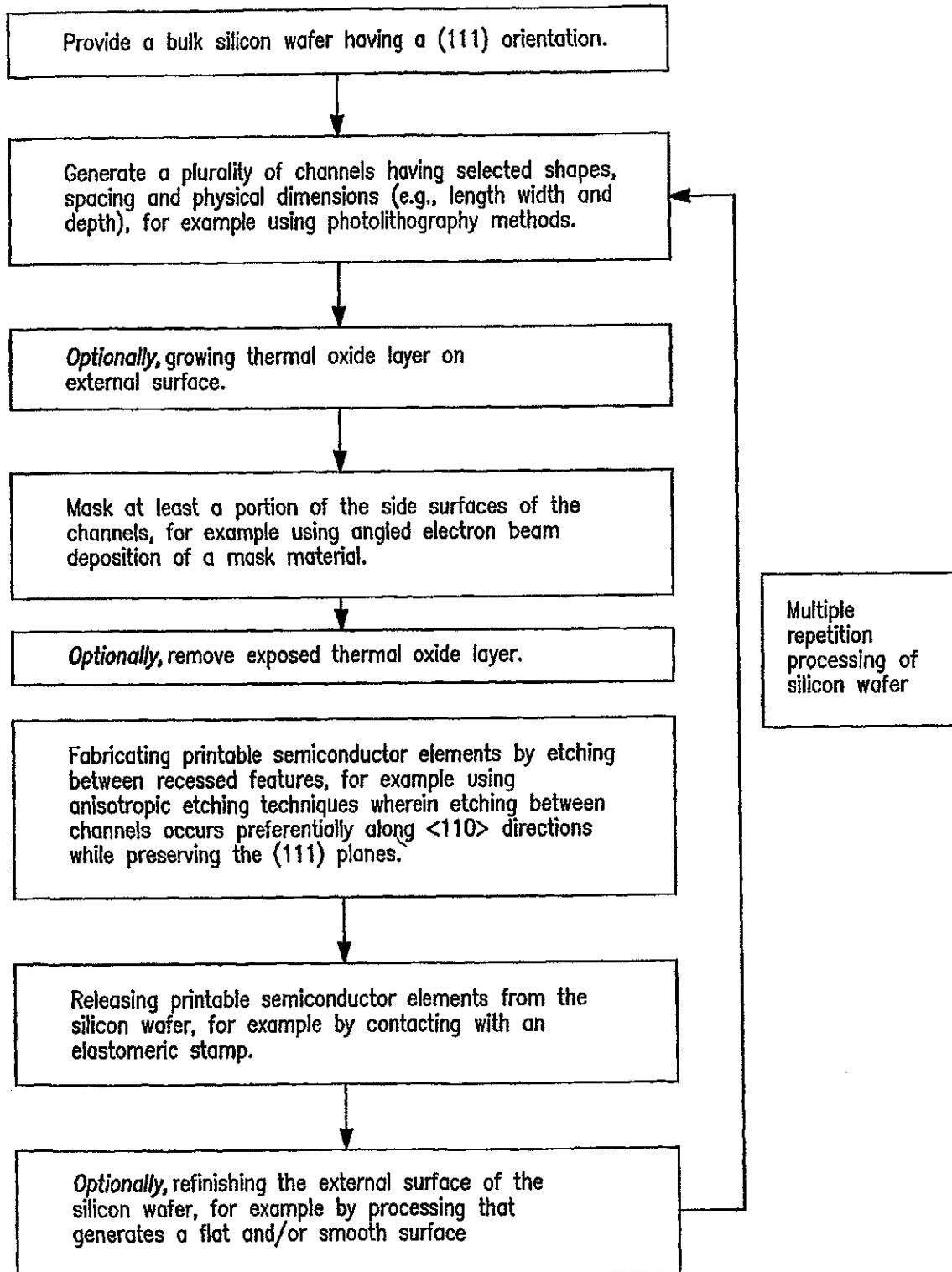


FIG. 1b

FIG. 1c



Anisotropic etching of unmasked regions;
generation of free-standing structures

FIG. 1d

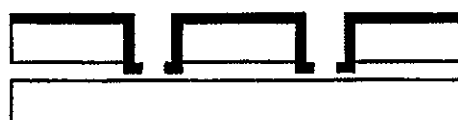


FIG. 1e



FIG. 1f



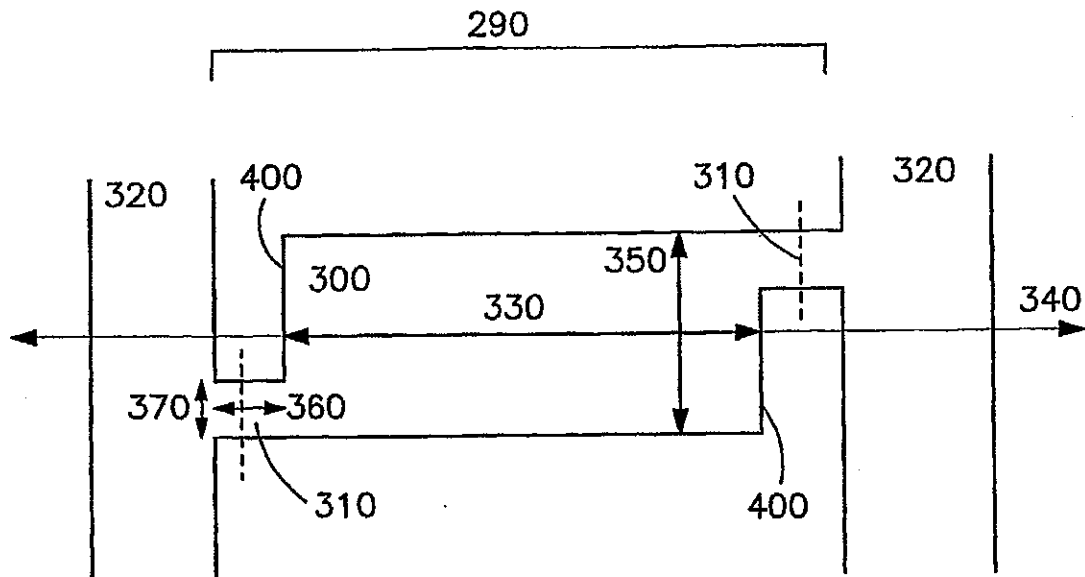


FIG. 2a

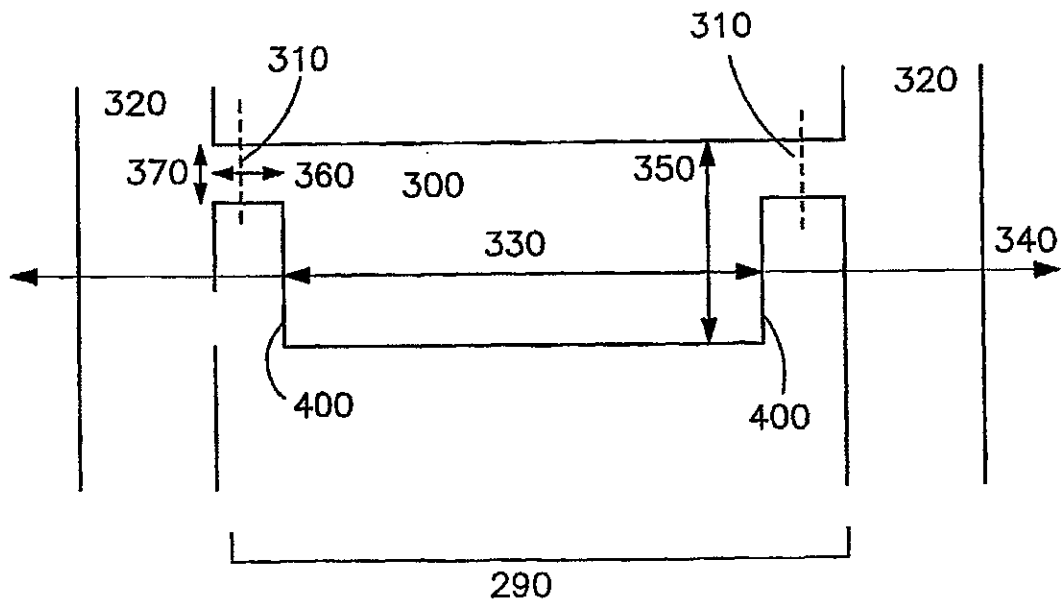


FIG. 2b

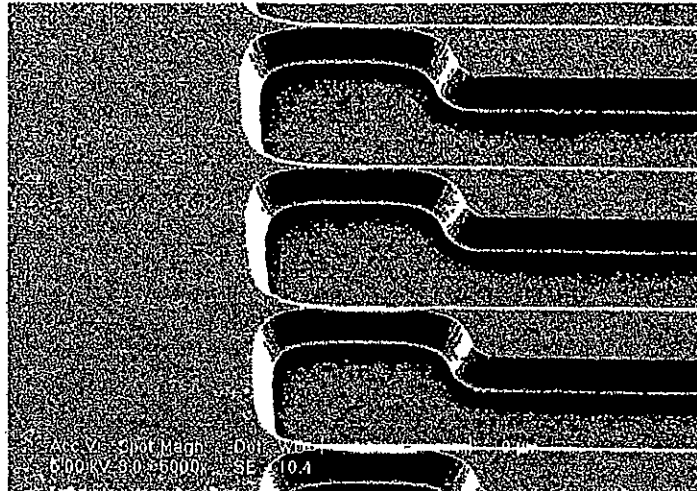


FIG. 2c

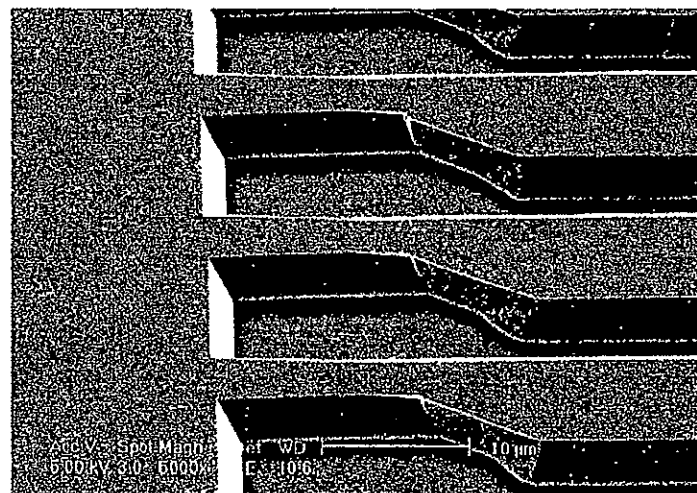


FIG. 2d

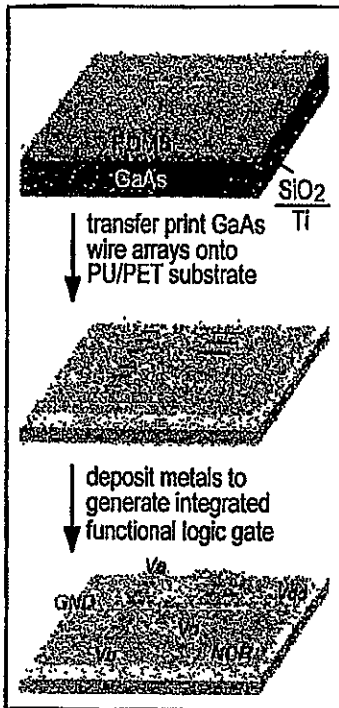


FIG. 3a

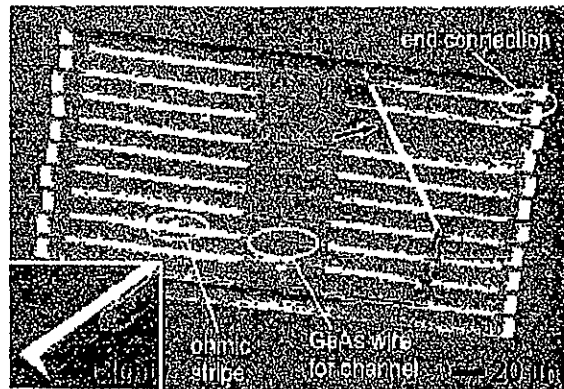


FIG. 3b

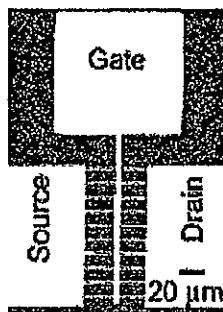


FIG. 3c

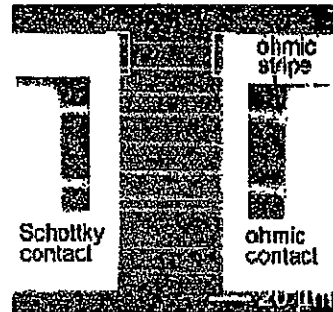


FIG. 3d

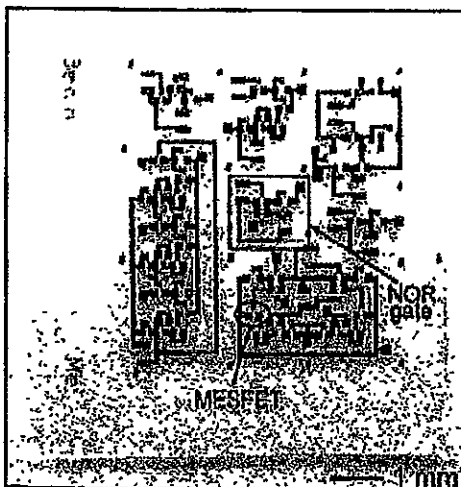


FIG. 3e

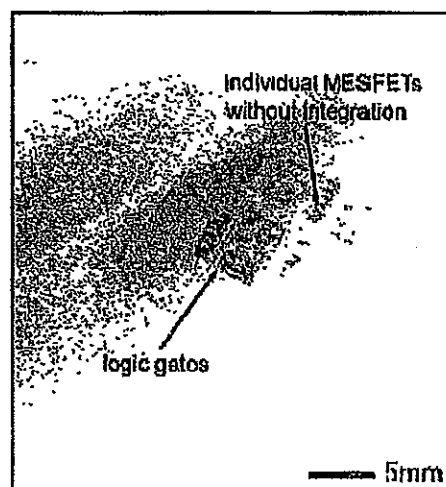


FIG. 3f

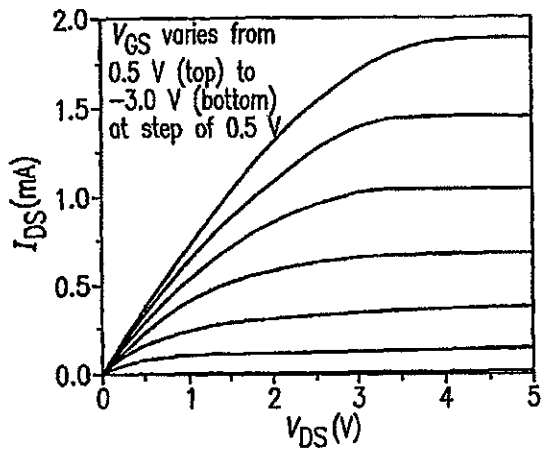


FIG. 4a

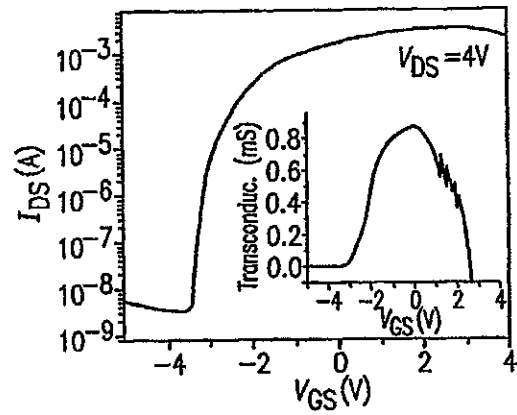


FIG. 4b

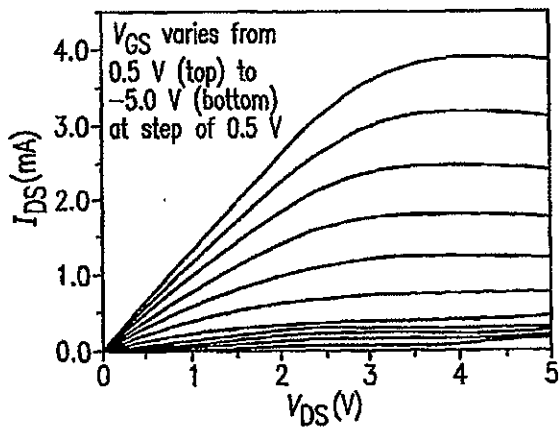


FIG. 4c

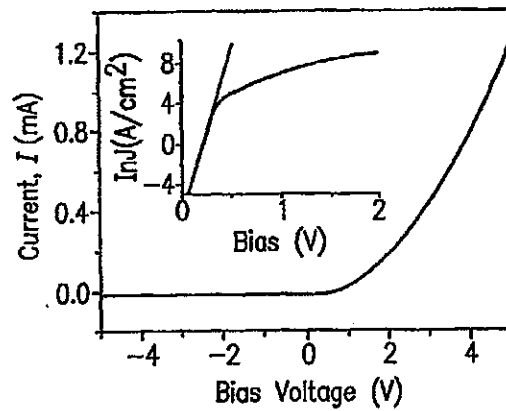


FIG. 4d

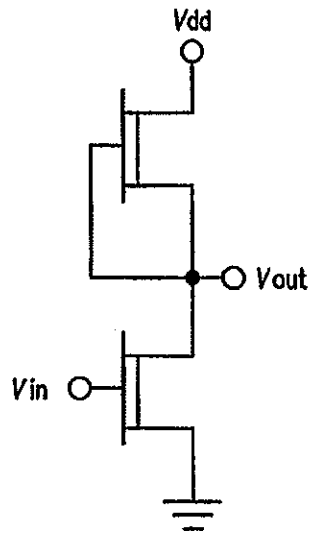


FIG. 5a



FIG. 5b

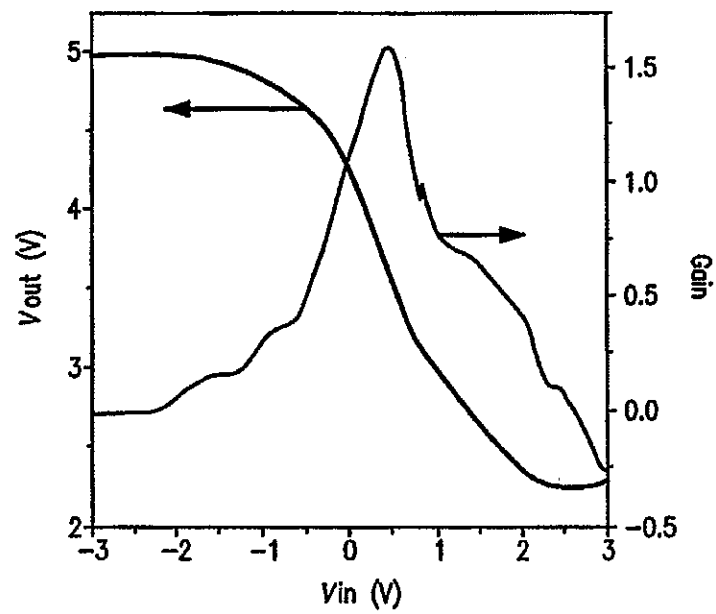


FIG. 5c

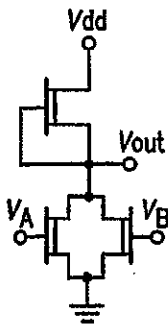


FIG. 6a



FIG. 6b

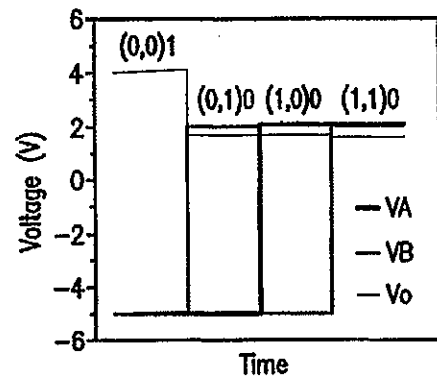


FIG. 6c

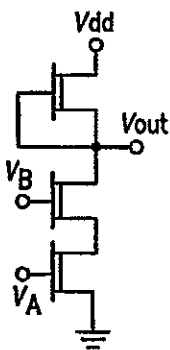


FIG. 6d

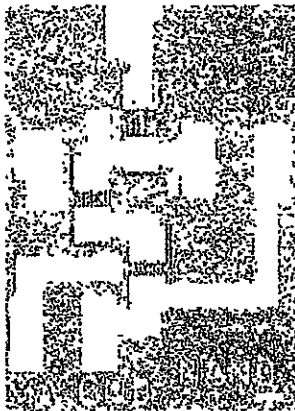


FIG. 6e

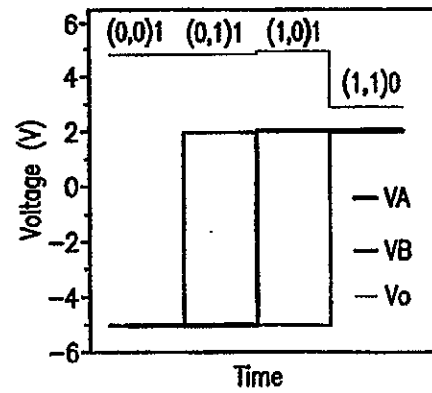


FIG. 6f



FIG. 7a

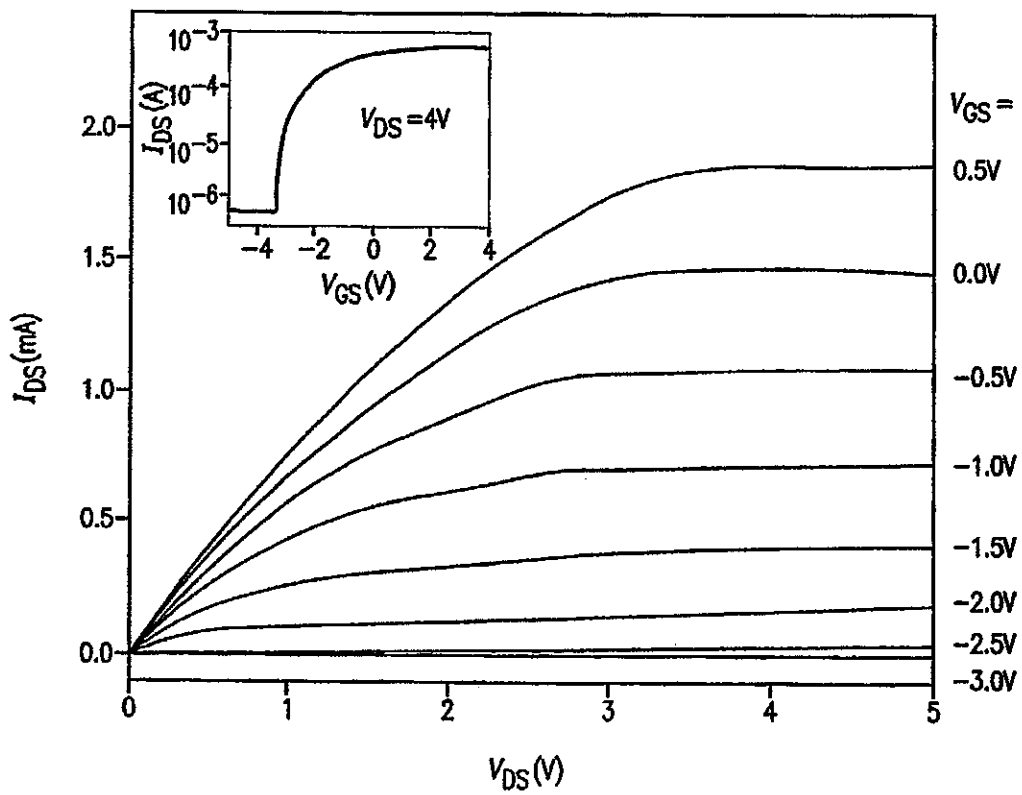


FIG. 7b

FIG. 8a

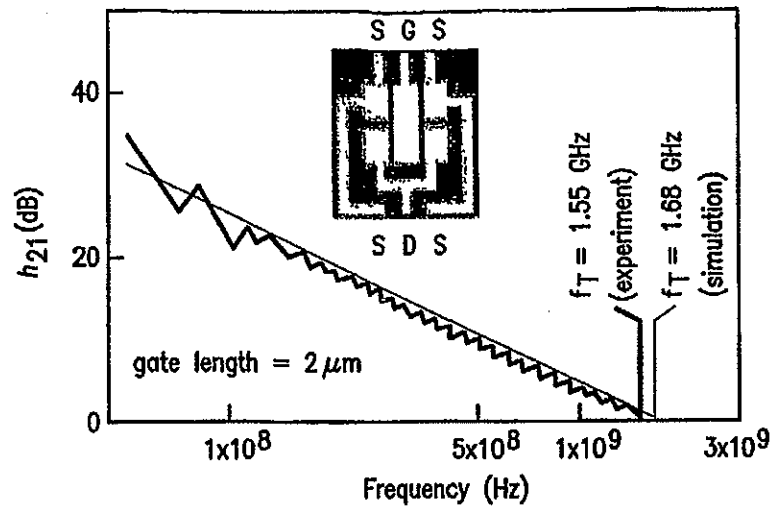


FIG. 8b

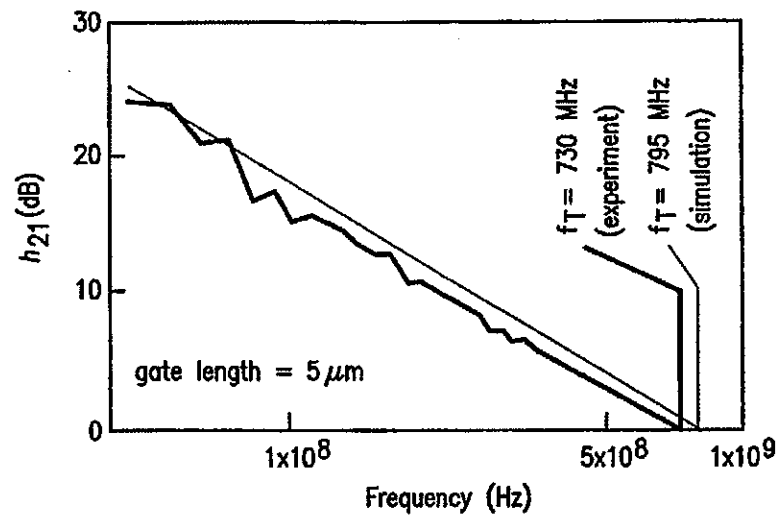


FIG. 8c

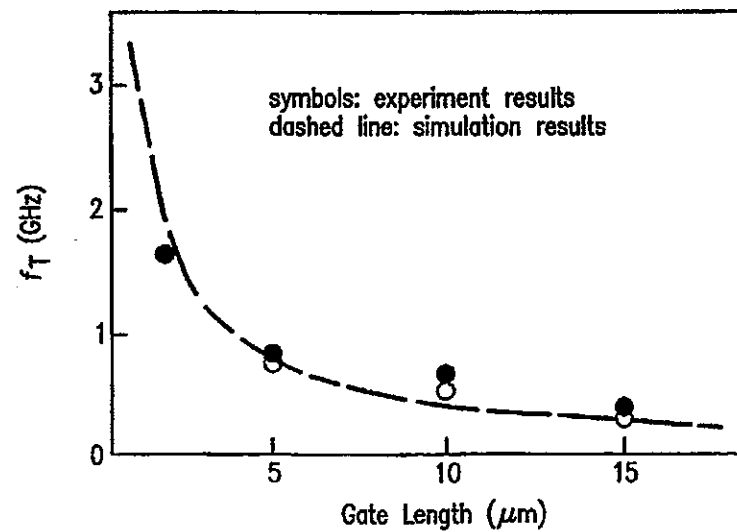


FIG. 9a

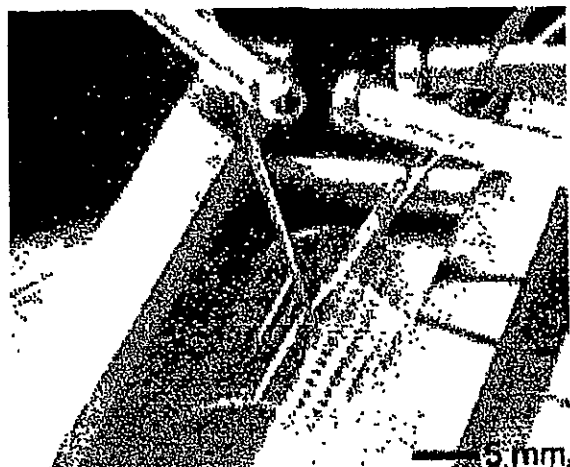


FIG. 9b

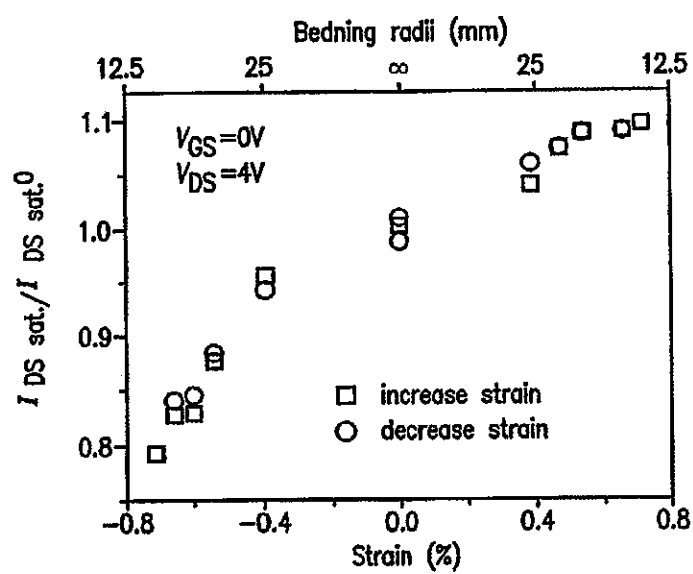
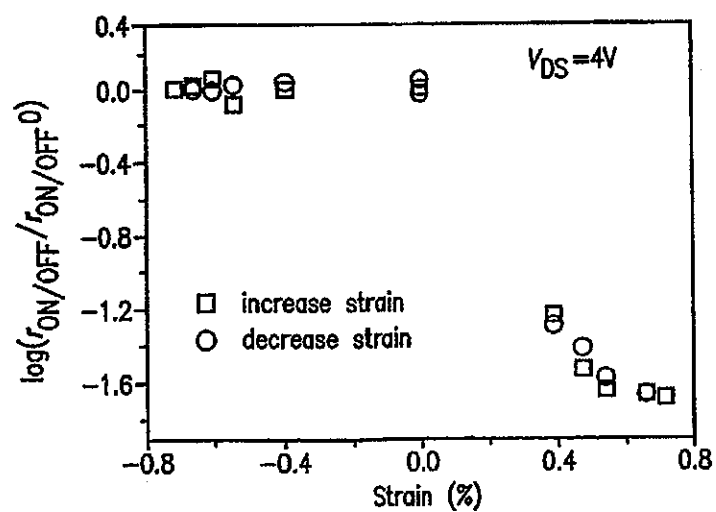
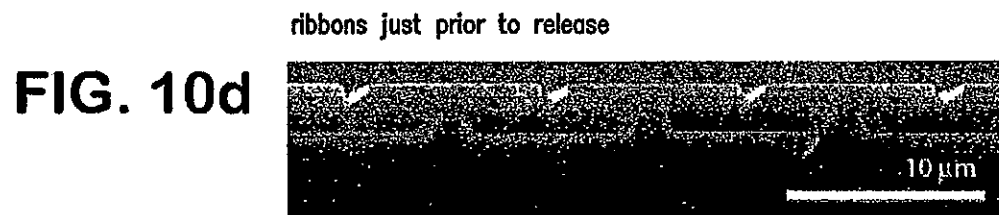
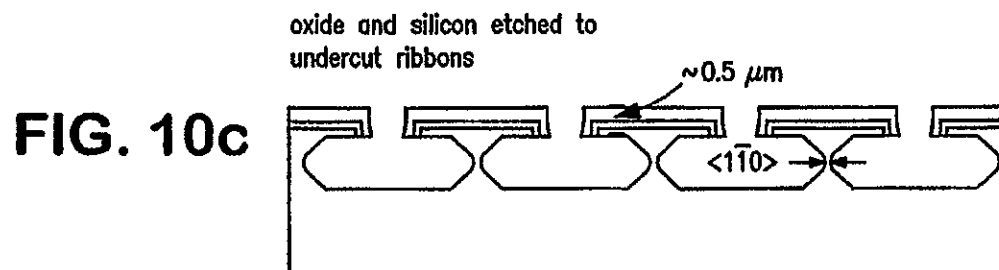
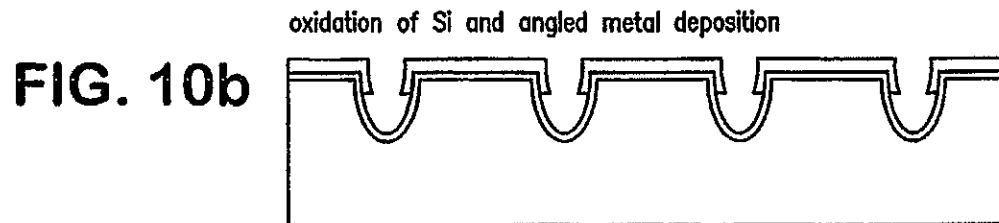
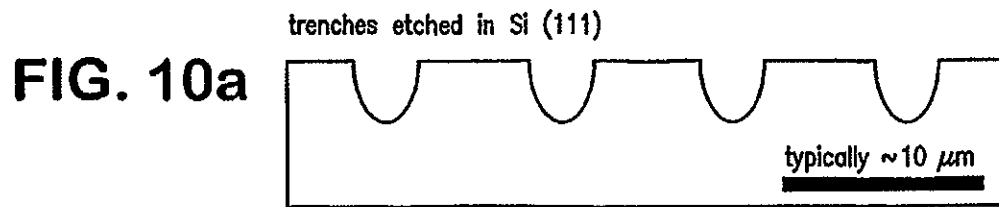


FIG. 9c





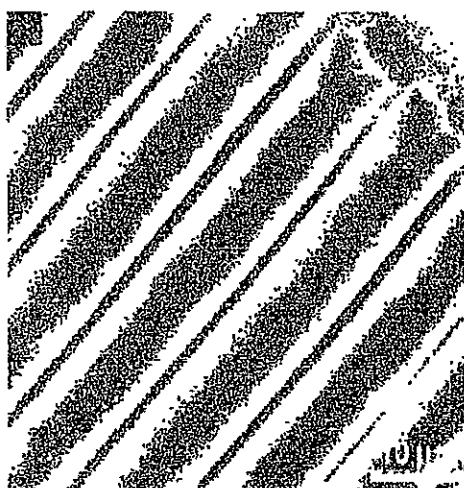


FIG. 11a

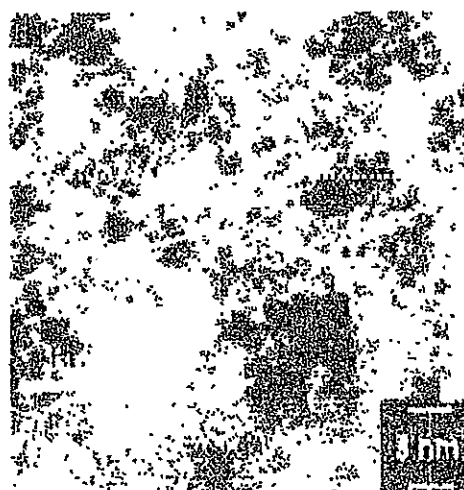


FIG. 11b

apply stamp to
donor substrate

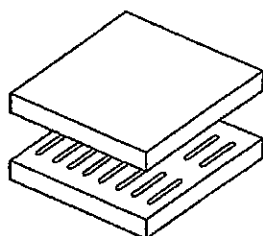


FIG. 12a

retrieve ribbons

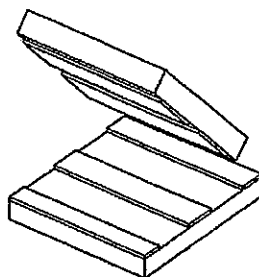


FIG. 12b

print ribbons onto
plastic sheet

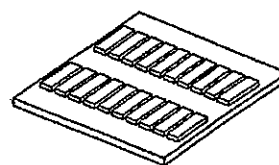


FIG. 12c

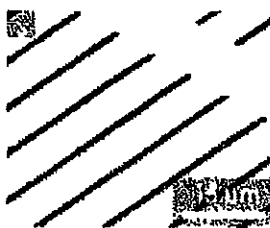


FIG. 12d



FIG. 12e



FIG. 12f

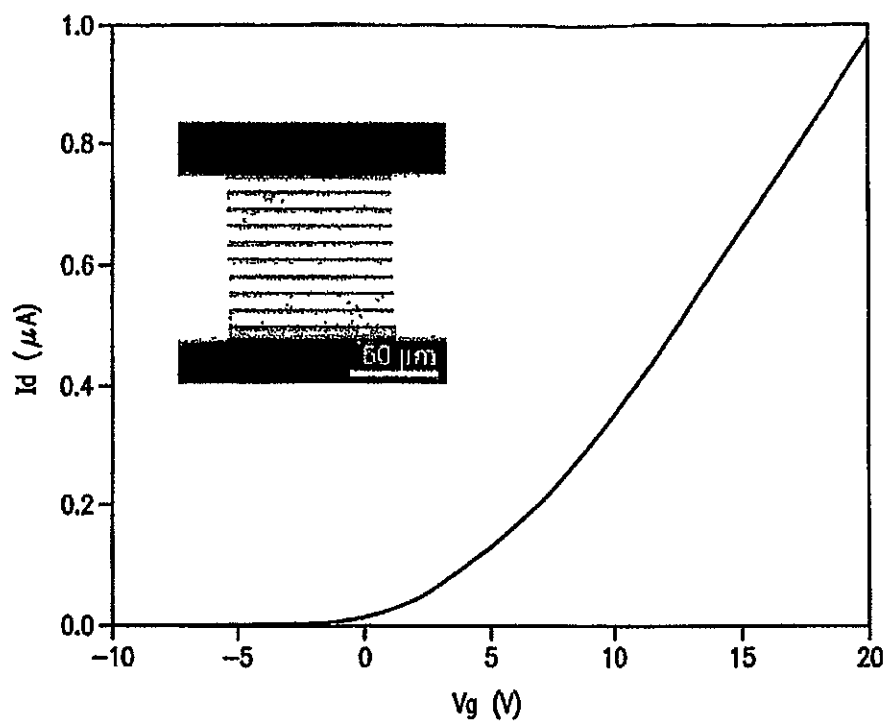
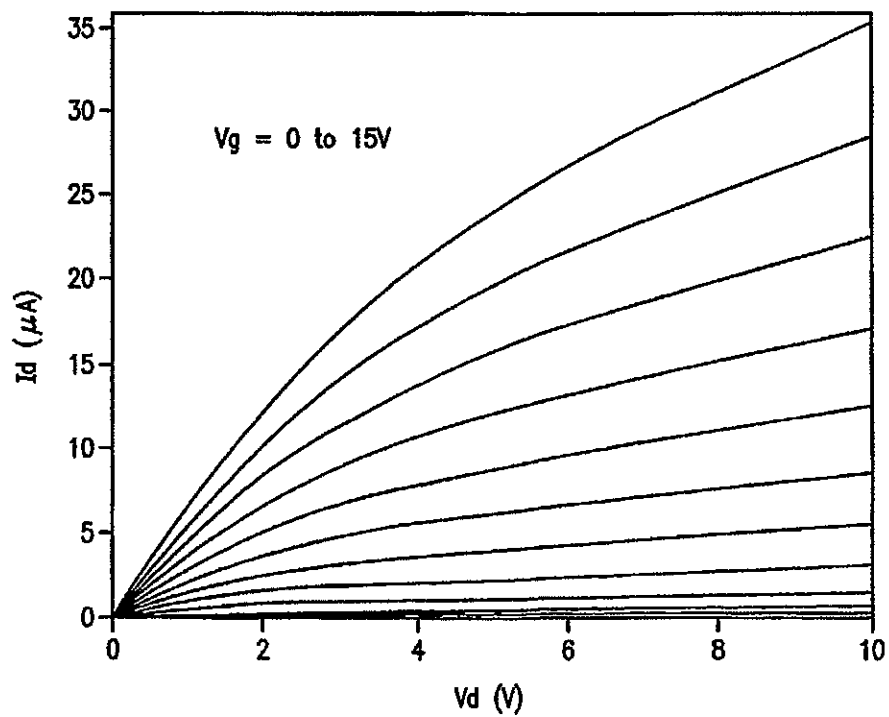
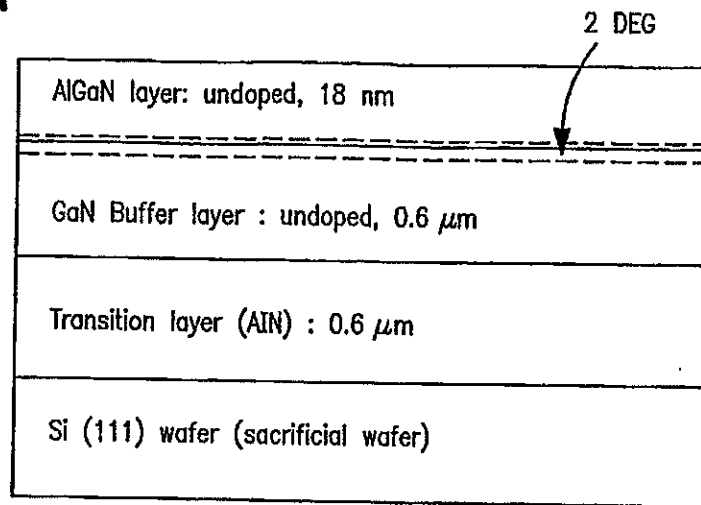
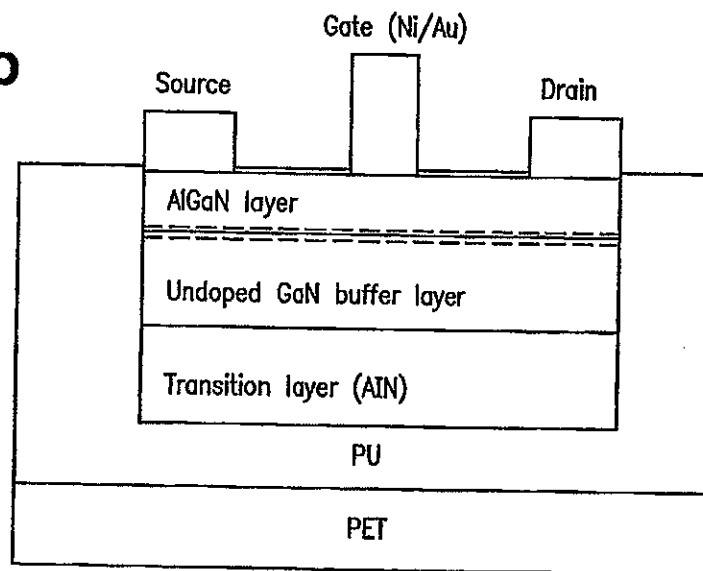
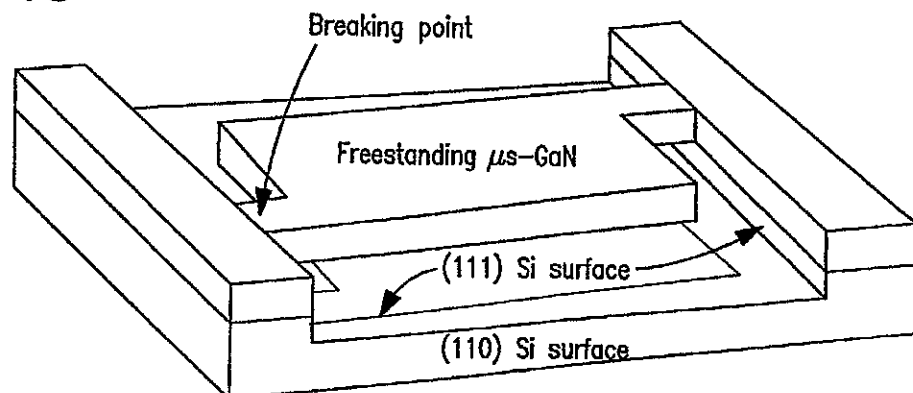
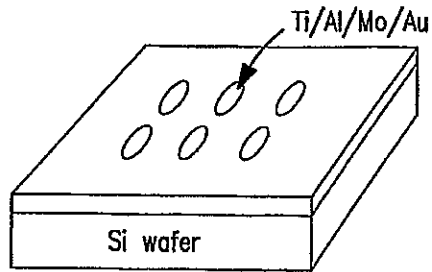
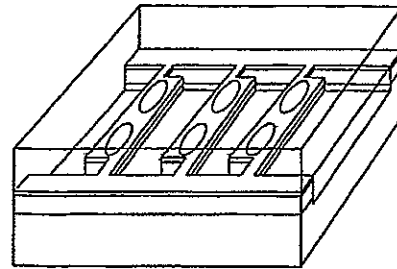
**FIG. 13a****FIG. 13b**

FIG. 14a**FIG. 14b****FIG. 14c**

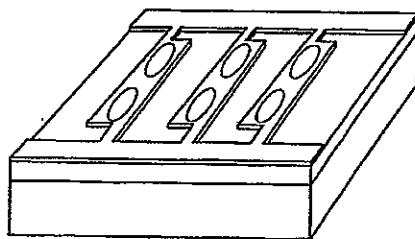
Ohmic contact on GaN stack

**FIG. 15a**

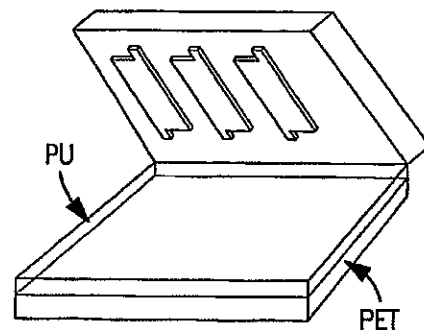
Transfer to PDMS

**FIG. 15e**

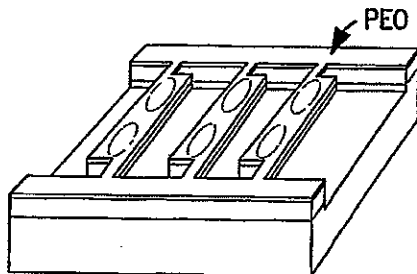
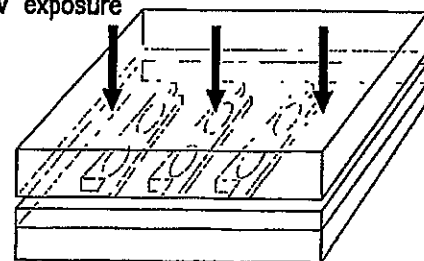
Ribbon pattern with PEO/Cr

**FIG. 15b**

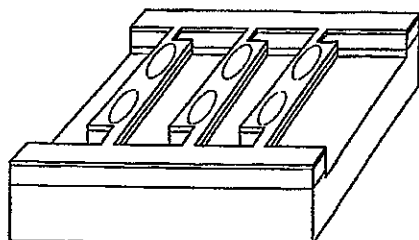
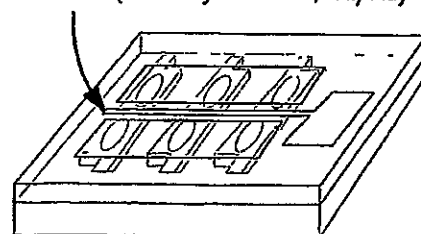
Spincast PU on plastic

**FIG. 15f**

ICP etching of GaN

**FIG. 15c**Contact PDMS to PET
UV exposure**FIG. 15g**

TMAH etching of underlying Si

**FIG. 15d**Removing oxide & metal contact
Gate (Schottky contact, Ni/Au)**FIG. 15h**

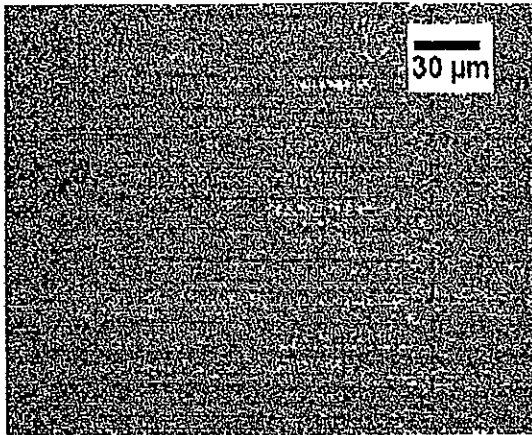


FIG. 16a

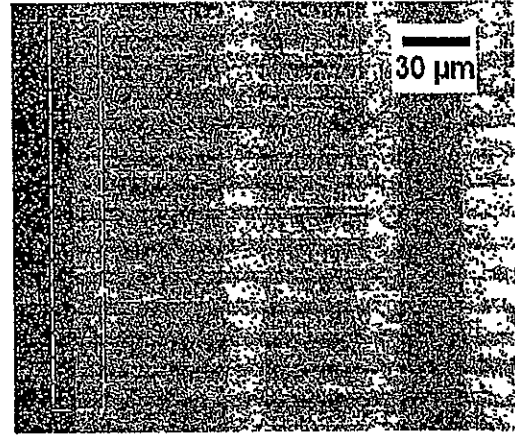


FIG. 16b

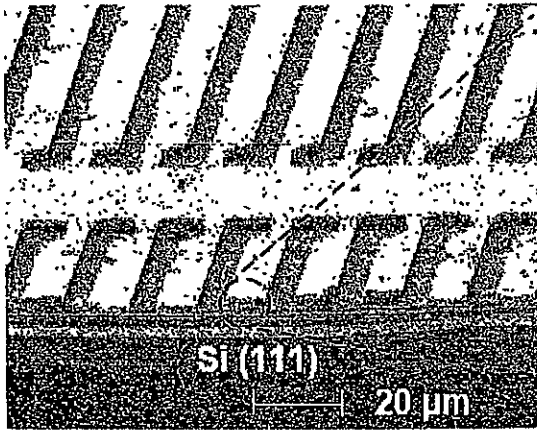


FIG. 16c

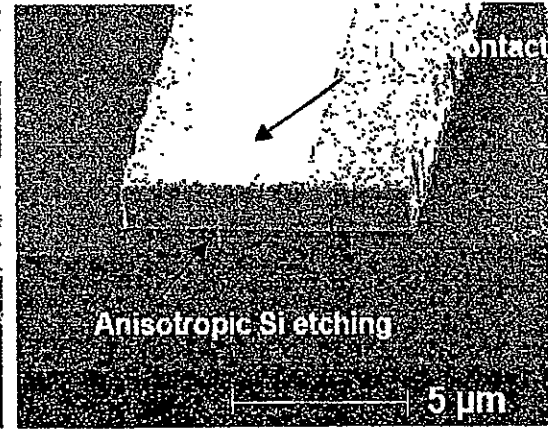


FIG. 16d

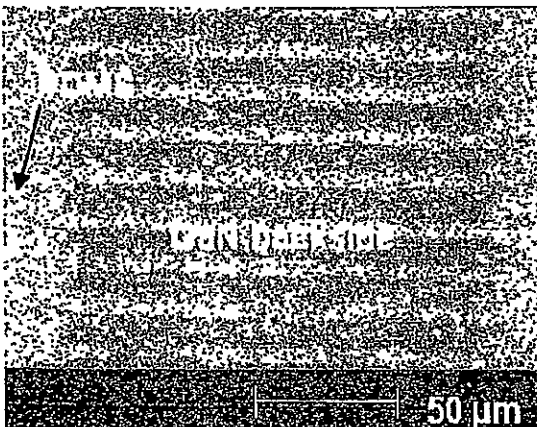


FIG. 16e

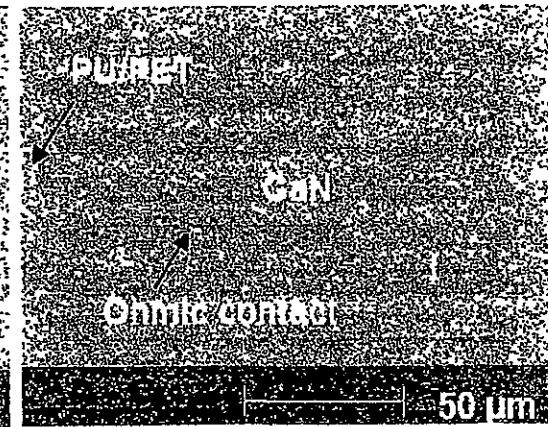


FIG. 16f

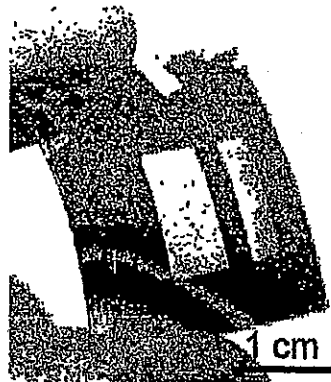


FIG. 17a

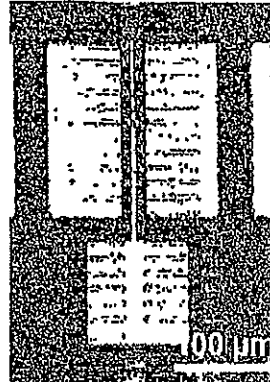


FIG. 17b

FIG. 17c

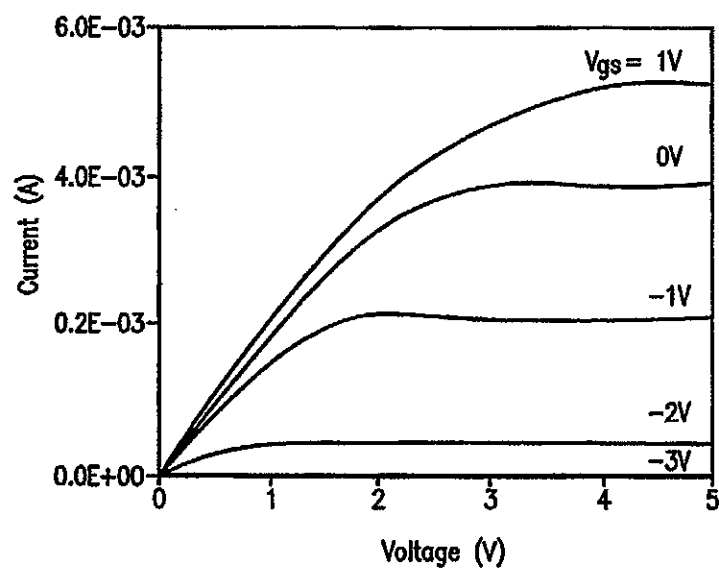


FIG. 17d

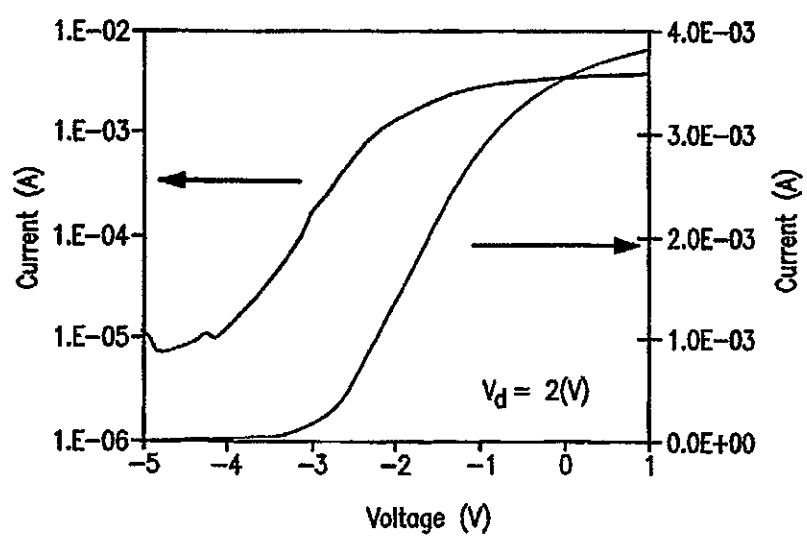


FIG. 18a

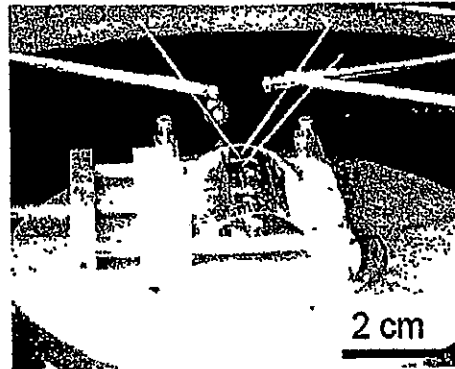


FIG. 18b

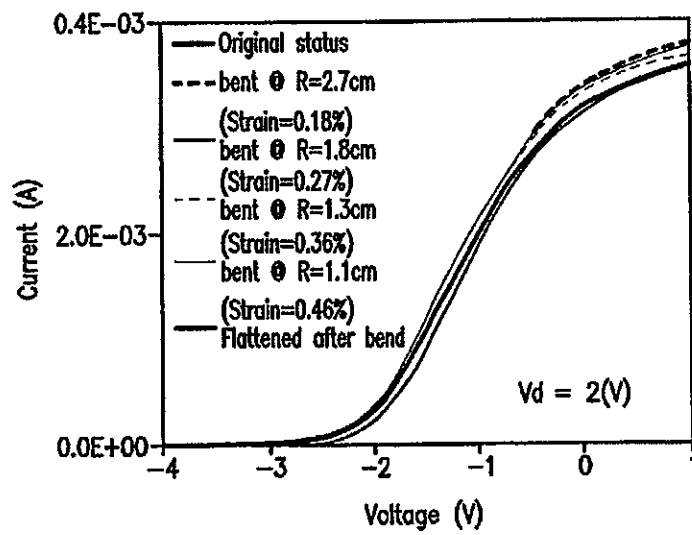
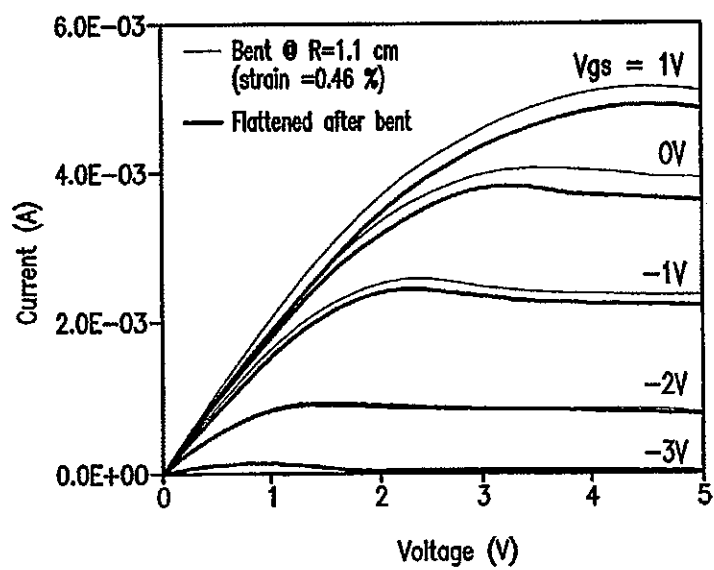


FIG. 18c



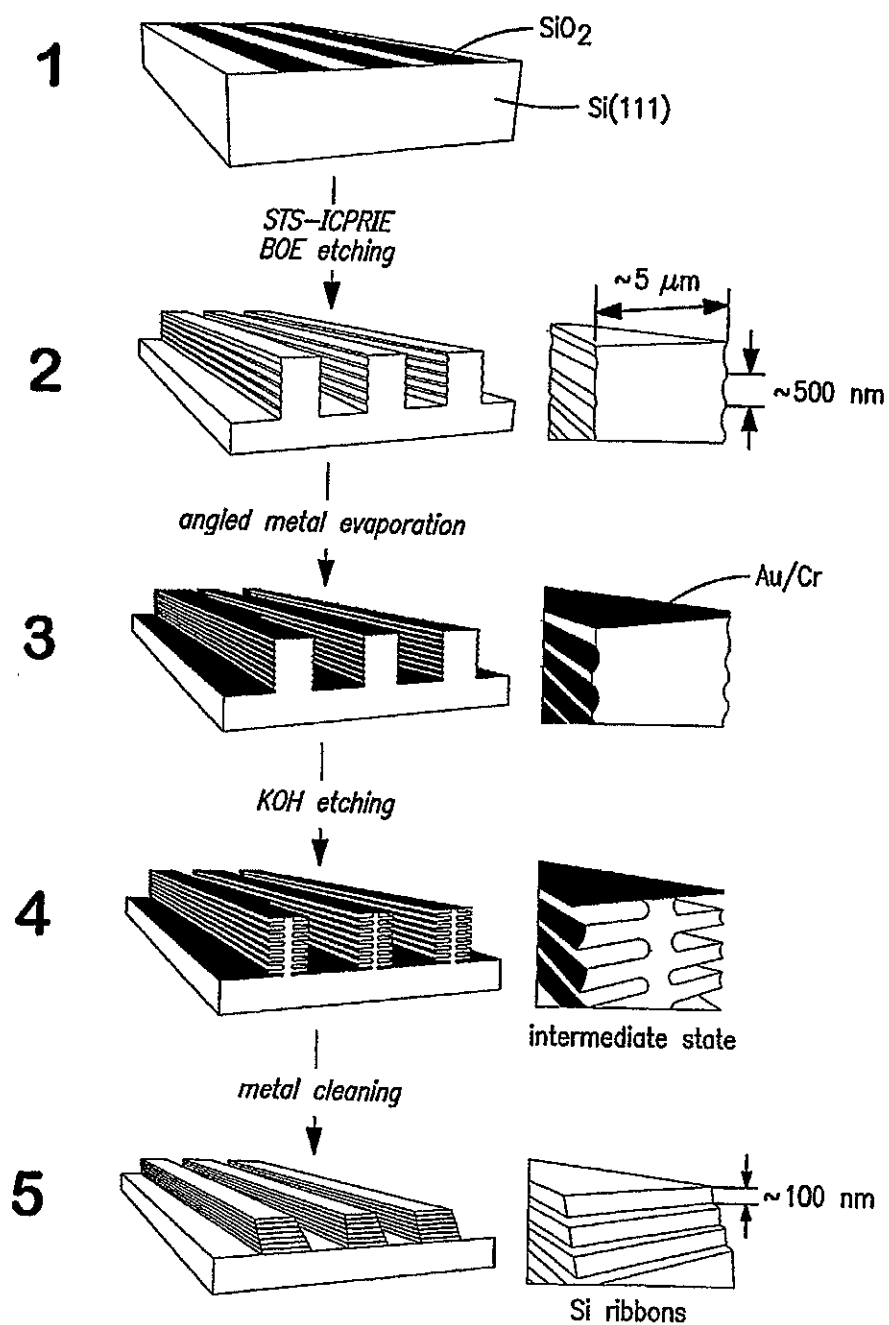


FIG. 19

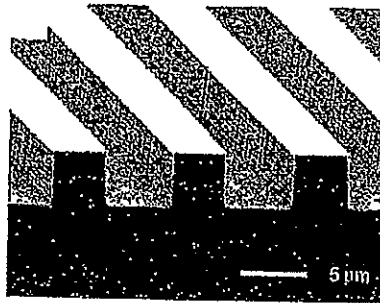


FIG. 20a

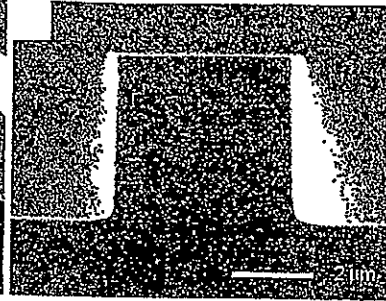


FIG. 20b

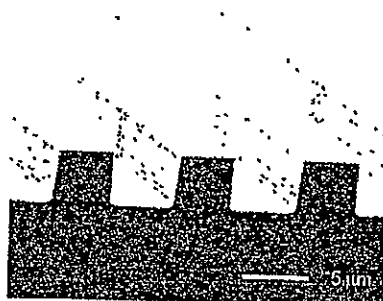


FIG. 20c

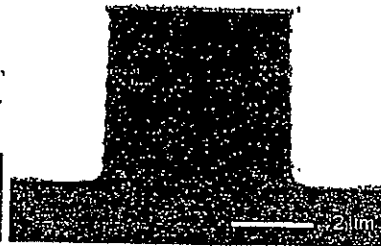


FIG. 20d

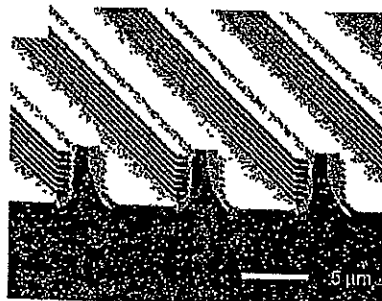


FIG. 20e

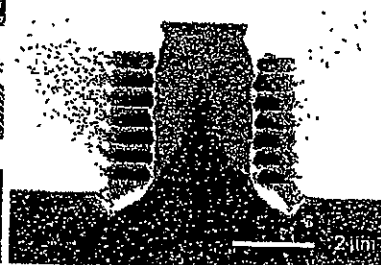


FIG. 20f

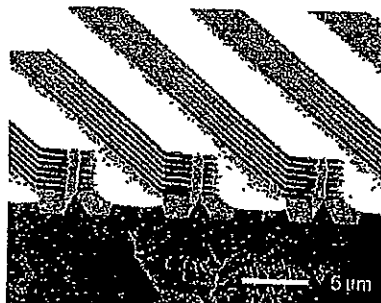


FIG. 20g

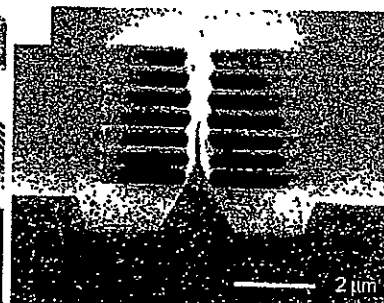


FIG. 20h

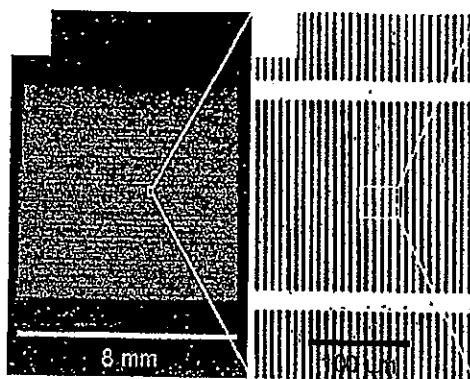


FIG. 21a **FIG. 21b**

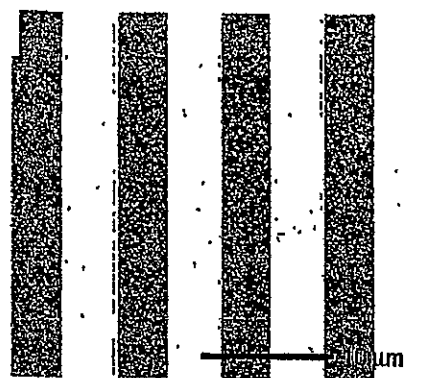


FIG. 21c

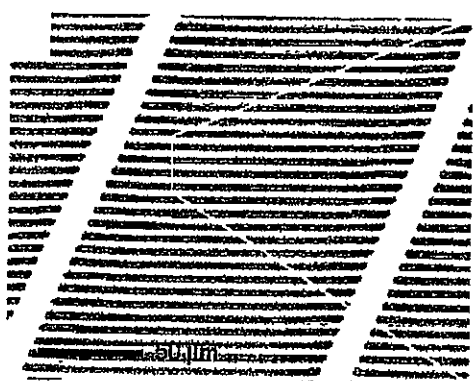


FIG. 21d

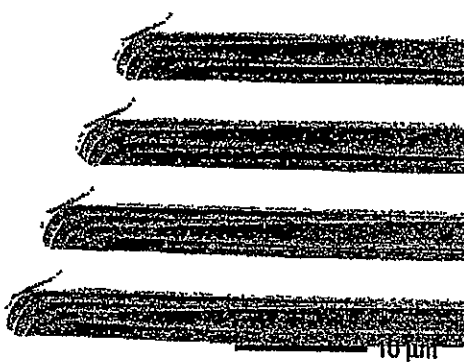


FIG. 21e



FIG. 22a

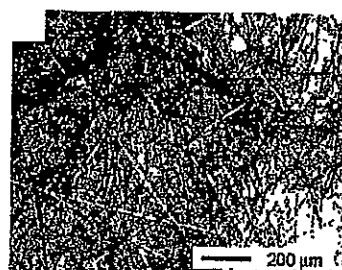


FIG. 22b

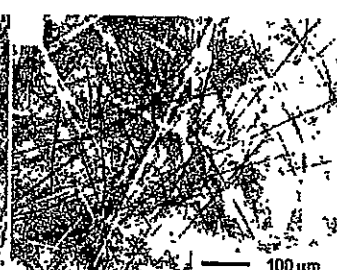


FIG. 22c

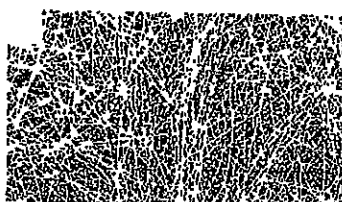


FIG. 22d



FIG. 22e



FIG. 22f

FIG. 23a

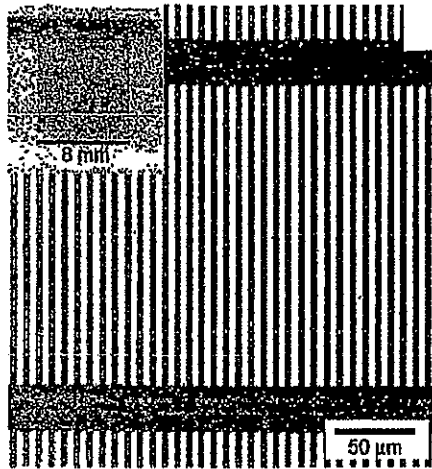


FIG. 23b

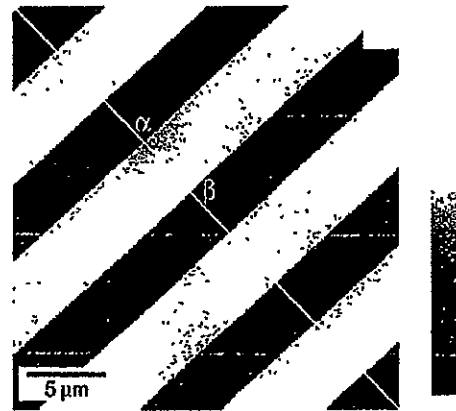


FIG. 23c

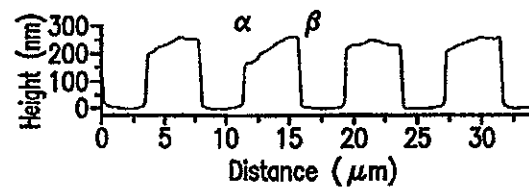


FIG. 23d

